- # Thin Film Annealing
  - ## Backend Vacuum Annealing Furnace

Annealing Library

- No element of III-V group.
- Low volatility.
- Each sample should not smaller than one quarter of 6 or 4 inches.

High Vacuum Mode

- Ambient：O_2 or N_2
- Temperature：RT ~ 600℃
- Maximum gas flow rate：O_2 (30 sccm) and N_2 (120 sccm)

Low Pressure Mode

- Pressureabout：10^{-7} torr
- Temperature：RT ~ 600℃